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**Ishigami et al.**

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(54) **HIGHLY PURIFIED TITANIUM MATERIAL,  
METHOD FOR PREPARATION OF IT AND  
SPUTTERING TARGET USING IT**

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patent is extended or adjusted under 35  
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This patent is subject to a terminal dis-  
claimer.

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#### **Related U.S. Application Data**

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No. 08/028,084, filed on Mar. 8, 1993, now Pat. No. 5,584,  
906, which is a division of application No. 07/924,770, filed  
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#### **(30) Foreign Application Priority Data**

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H01L 29/40

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257/770

(58) **Field of Search** ..... 257/763, 751,  
257/750, 758, 764, 770, 709

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#### **(57) ABSTRACT**

The crude Ti particles prepared by molten salt electrolysis or  
Iodide method are classified into each particle diameter  
according to contents of impurities, and the crude Ti par-  
ticles having a desired particle diameter are selected from  
the crude Ti particles classified depending on each particle  
diameter. Otherwise, the crude Ti particles are acid-treated.  
Then they are electron-beam-melted. Through the above  
production process, there is prepared a highly purified Ti  
material having an oxygen content of not more than 350  
ppm, Fe, Ni and Cr contents of not more than 15 ppm each,  
Na and K contents of not more than 0.5 ppm each, a  
reduction of area as a material characteristic of not less than  
70%, and a thermal conductivity of not less than 16 W/m K.  
In short, the highly purified Ti material satisfying high  
purity, good processability and good thermal conductivity  
can be obtained. A film having more uniform thickness of  
film and inside structure can be obtained from a sputtering  
target prepared using the above highly purified Ti material.

**14 Claims, 3 Drawing Sheets**

